



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1765
Examiner: To be assigned

In Re PATENT APPLICATION OF:

Applicant(s) : Toyo Kazu SAKATA

Serial No. : 10/721,260

Filed : November 26, 2003

For : Etching method and semiconductor device
fabricating method

Attorney Ref: TAI 145

STATUS REQUEST

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please let us know the status of the above-identified application and when an Action may be expected. Please respond via facsimile or e-mail Tonya Harris (Docketing Manager) at tonya@rabinchamp.com.

Respectfully submitted,

Steven M. Rabin

June 2, 2005
Date

SMR:klc

Steven M. Rabin
Registration No. 29,102
Customer No. 23,995
Tel: (202) 371-8976
Fax: (202) 408-0924